FORM PTO – 1449 INFORMATION DISCLOSURE STATEMENT	ATTY DOCKET NO.: QCS-001DV3 APPLICANT: KAMIENIECKI et al. SERIAL NO.: ~~Not yet assigned~~ 09/932754 FILING DATE: August 17, 2001 GROUP: Not yet assigned

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		"Frequency Dependence of Photo-EMF of Strongly Inverted Ge and Si MIS Structures-II. Experiments", by R.S. Nakhmanson, et al., Solid-State Electronics, 1975, Vol. 18, pp. 627-634
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EXAMINER John M. Hoyte	DATE CONSIDERED 5/5/02

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